

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Hiroshi NOMURA et al.) Parent Group Art Unit: 2851
)
Cont. of Application No.: 09/923,443) Parent Examiner: D. Esplin
)
Filed: Herewith)
)
For: EVALUATION MASK, FOCUS)
MEASURING METHOD AND)
ABERRATION MEASURING)
METHOD)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

PRELIMINARY AMENDMENT

Please amend the specification as set forth in this paper.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims begin on page 3 of this paper.

Remarks begin on page 11 of this paper.

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